

Supplementary Information

Suppression of metal to insulator transition using strong interfacial coupling at cubic and orthorhombic perovskite oxide heterointerface

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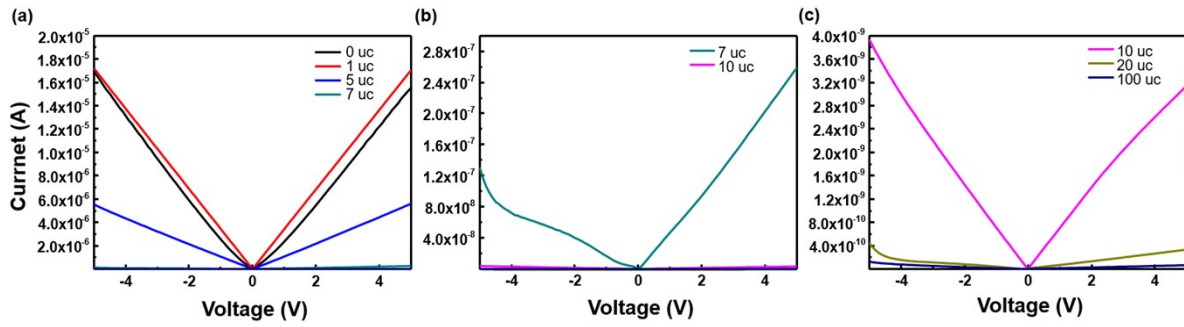


Fig. S1. I-V curves of the LAO/CTO/STO heterostructures with different CTO interlayer thicknesses: (a) 0 - 7 uc, (b) 7 and 10 uc, (c) 10 - 100 uc.

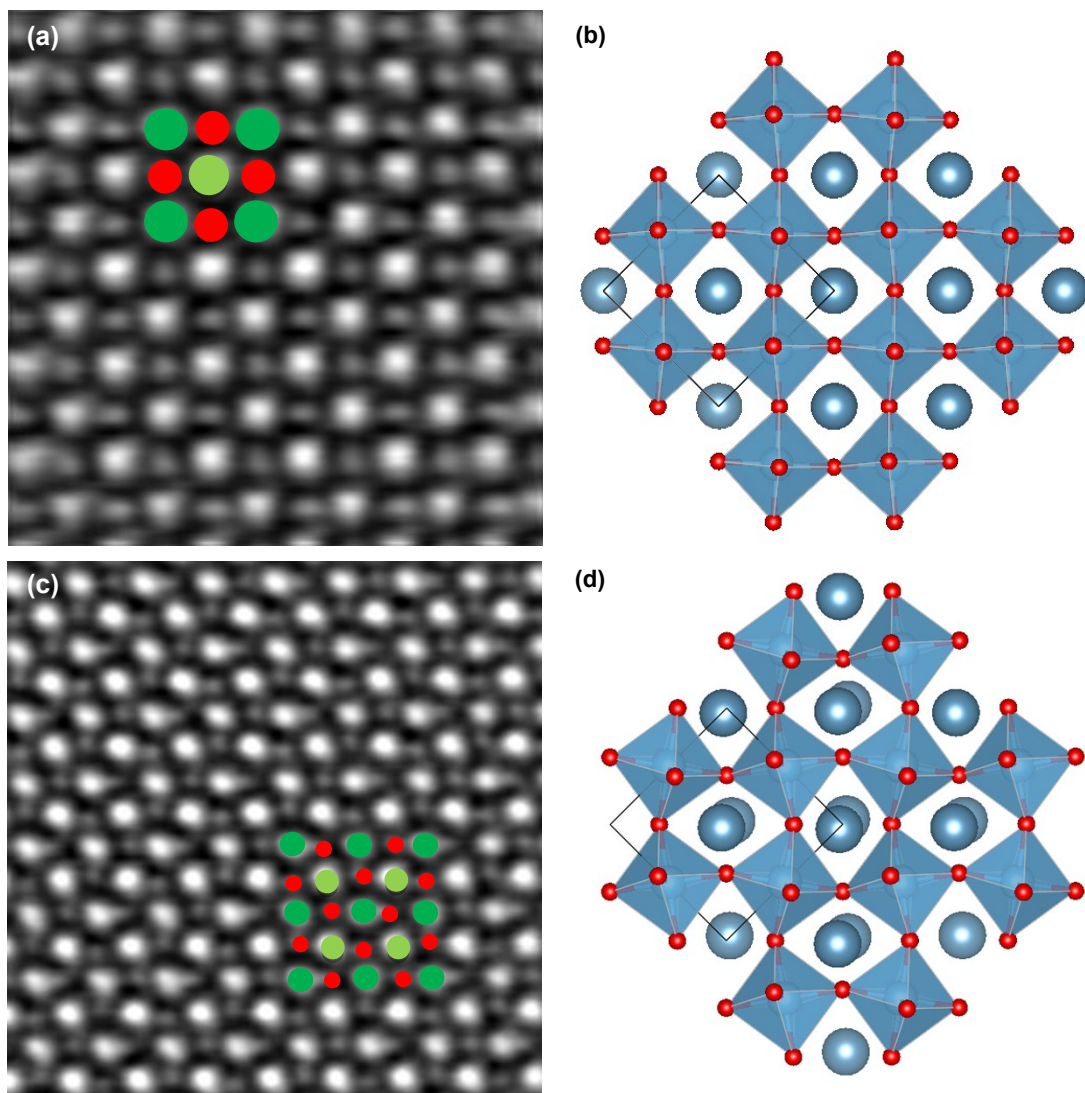


Fig. S2. (a) Magnified iDPC STEM image of the 5 uc CTO film in the zone axis of $[100]_p$ with marked atom position. (b) Atomic model of 5 uc CTO film, showing near-cubic symmetry. (c) Magnified iDPC STEM image of the 24 uc CTO film in the zone axis of $[100]_p$ with marked atom position. (d) Atomic model of 24 uc CTO film, showing orthorhombic symmetry.

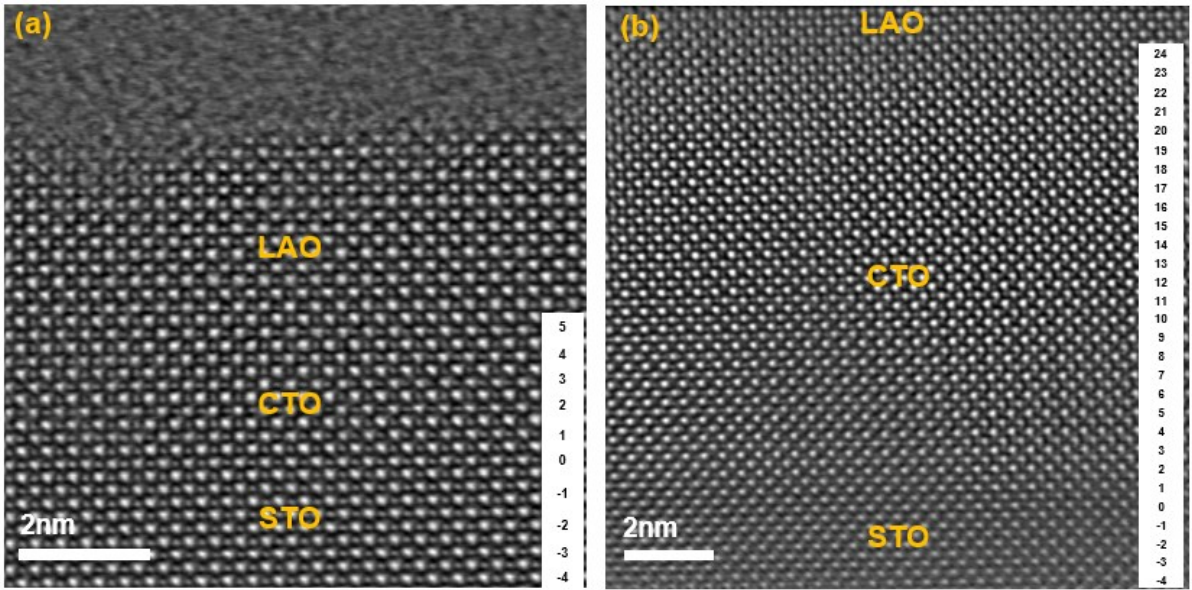


Fig. S3. iDPC STEM image of the (a) LAO/CTO (5 uc)/STO and (b) LAO/CTO (24 uc)/STO heterostructure with atomic row position at which Ti-O-Ti bonding angles are measured.